



Attorney Docket No.: 28955.1048

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No. 10/531,208

Confirmation No. 6424

In re Application of

MITSURU UEDA, *et al.*

Art Unit: 1795

Filed: April 14, 2005

Examiner: Sin J. Lee

For: PHOTORESIST BASE MATERIAL, METHOD FOR PURIFICATION THEREOF, AND PHOTORESIST COMPOSITIONS

US PATENT AND TRADEMARK OFFICE
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Entered
w/ RCE
5/12/08

W.M.
5/21/08

DO NOT ENTER: /SL/

AMENDMENT UNDER 37 C.F.R. § 1.116

In response to the Office Action mailed December 11, 2007, please amend the above-identified patent application as follows:

DO NOT ENTER: /SL/

/Sin Lee/